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PII: S0040-6090(17)30837-4

DOI: doi:10.1016/j.tsf.2017.11.003

Reference: TSF 36335

To appear in: Thin Solid Films

Received date: 23 June 2017
Revised date: 14 October 2017
Accepted date: 2 November 2017

Please cite this article as: D.A. Minkov, G.M. Gavrilov, G.V. Angelov, J.M.D. Moreno, C.G. Vazquez, S.M.F. Ruano, E. Marquez, Optimisation of the envelope method for characterisation of optical thin film on substrate specimens from their normal incidence transmittance spectrum. The address for the corresponding author was captured as affiliation for all authors. Please check if appropriate. Tsf(2017), doi:10.1016/j.tsf.2017.11.003

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Optimisation of the envelope method for characterisation of optical thin film on substrate specimens from their normal incidence transmittance spectrum

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Abstract: The spectroscopic ellipsometry is the main tool for optical characterization of a thin film in its spectral region of strong absorption, where its transmittance spectrum does not contain interference pattern. The envelope method (EM) is the main tool for accurate optical characterisation of a thin film with thickness typically in the range [500, 5000] nm on a substrate,

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